

2020 EUVL Webinar

April 14, 2020

Held Online

Webinar Proceedings



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- [**SPIE Advanced Lithography –EUV Highlights**](#)
Mike Lercel
ASML
- [**Update of >300W High Power LPP-EUV Source Challenge for Semiconductor HVM**](#)
Hakaru Mizoguchi
Gigaphoton
- [**Recent progress on EUV Mask Development**](#)
Jinho Ahn
Hanyang Univ. and EUV-IUCC
- [**SPIE AL 2020 Resist Review and MTR Update**](#)
Alex Robinson
Irresistible Materials
- [**Resistless EUV Lithography**](#)
Yasin Ekinchi
PSI
- [**2020 SPIE AL –EUVL Conference Highlights and Road Ahead for EUVL**](#)
Vivek Baksh
EUV Litho, Inc.

